

Title (en)  
METHOD OF MANUFACTURING A POLISHING PAD

Title (de)  
VERFAHREN ZUM HERSTELLEN VON EINEM POLIERKISSEN

Title (fr)  
PROCEDE DE FABRICATION D'UN TAMPON DE POLISSAGE

Publication  
**EP 1011919 A1 20000628 (EN)**

Application  
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Priority  
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Abstract (en)  
[origin: WO9907515A1] Polishing pads are provided having a polishing surface formed from a hydrophilic material. The polishing surface has a topography produced by a thermoforming process. The topography consists of large and small features that facilitate the flow of polishing fluid and facilitate smoothing and planarizing.

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IPC 8 full level  
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